Description

The *FEI Nova NanoSEM 230* high resolution field emission SEM is our main imaging tool for nanoparticles, featuring 1nm resolution at 15 KV. A STEM II detector and a vCD detector (for beam deceleration imaging) have recently been added to the standard ETD and TLD detectors. Equipped with a JC Nabity Nanometer Pattern Generation System (NPGS 9.0) this NanoSEM can write patterns down to 20 nm feature sizes.

Configuration

- Detectors: TLD, ETD, vCD, & STEM-II
- Beam deceleration sample stage bias
- High Speed Beam Blanker
- NPGS 9 Beamwriting software

Training

Users may request training

Location

SEM Lab: ESB28B

Contact

Qiti Guo